



Electron Cooling

Developments for AD/LEIR e-cooling and Ionisation Profile Monitors

BE-BI-EA

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16th October 2014

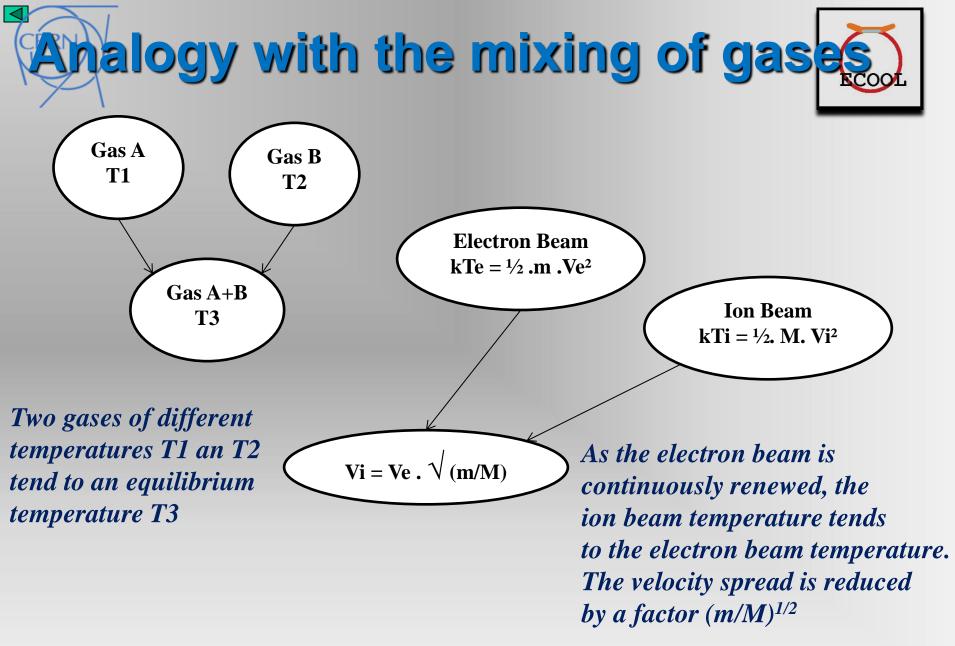
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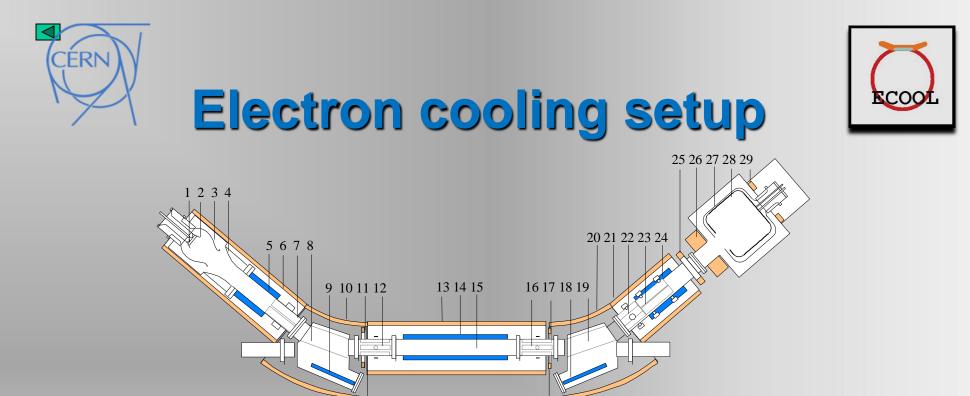
Slide 1





- Means to increase the phase space density of a stored ion beam.
- Mono-energetic cold electron beam is merged with ion beam which is cooled through Coulomb interaction.
- Electron beam is renewed and the velocity spread of the ion beam is reduced in all three planes.





- E-gun: thermocathode, Pierce shield, Grid control, accelerating anodes
 - final current given by Child's Law: $I = \mu .V^{3/2}$
 - the parameter μ is the perveance and is given by 7,3.10-6 $(r/d)^2$
- Interaction section
- Collector
- The whole system is immersed in a longitudinal field

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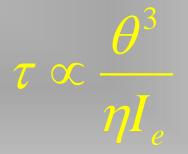
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• Electron cooling theory gives :



- where Θ is the relative difference in angle between the ions and electrons $(\theta_i - \theta_e), [\theta_i = \sqrt{(\varepsilon/\beta)}]$
- the parameter $\eta = L_{cooler} / L_{machine}$
- and I_e is the electron current.



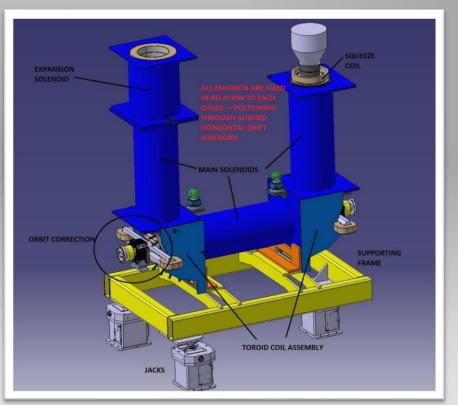


- Improve the quality of low energy ion beams
 - many experiments on LEAR and AD not possible without electron cooling
 - used to cool (anti)protons, H⁻, oxygen, lead and argon ions
 - first electron cooling device to be used routinely on a storage ring
- Increase of the duty cycle of the machine
 - cooling time much less than what can be obtained with stochastic cooling at low energies (< 310 MeV/c)
- LHC and North Area request a variety of ions
 - the injection scheme requires fast cooling times and stacking



ELENA e-cooler





- ELENA decelerator will increase X 100 the number of antiprotons for experiments.
- E-cooler will generate a cold and stable e-beam @ 55 eV in order to cool the 100 keV antiprotons.

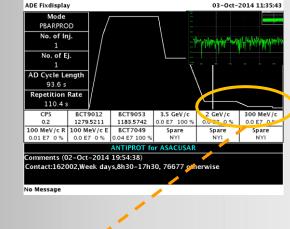
Momentum	35 MeV/c	13.7 MeV/c
Pbar-beam energy	648 keV	100 keV
E-beam energy	355 eV	55 eV
I e	5 mA	2 mA
Bgun	1000 G	
Bdrift	100 G	
Toroid bending radius	0.25 m	
Cathode radius	8 mm	
E-beam radius	25 mm	
Cooling drift length	1.0 m	

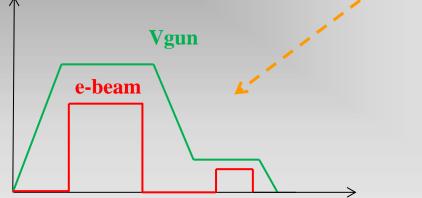
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Eliminate the "parasitic" electrons beam due to the latency of the Gun high power voltage supply for the AD machine.

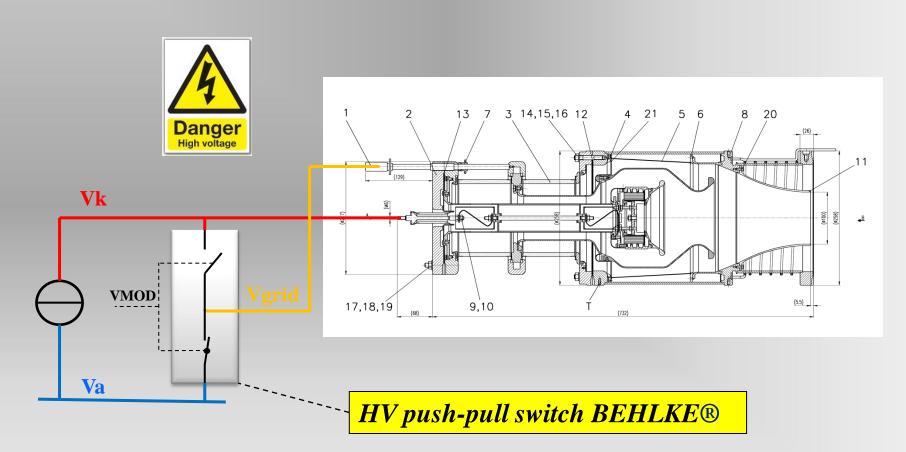








HV Switch



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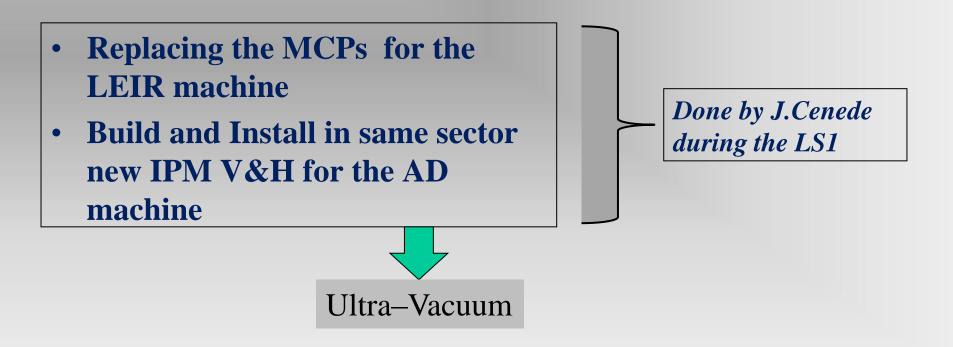
HV Switch

- The first manipulations show that the HV switch works fine when the Cathode is cold (e-beam=0).
- As soon as we have started the tests with the production of electrons a threshold appeared at ~85% of the maximum value.
- Variations on Vgrid ($Va \pm \Delta V$) have confirmed that the threshold is a <u>e-beam threshold</u> (electron cloud arising inside the gun ?).

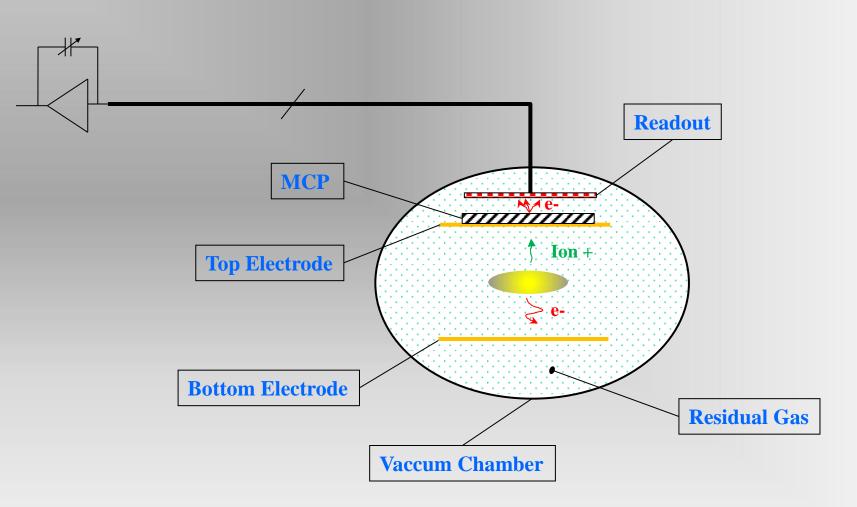
Ie = (μ / μ ') V^{3/2} with μ '=virtual perveance (>1)



• Design, build and install a new and common electronics for the AD & LEIR IPM for both H & V plan.



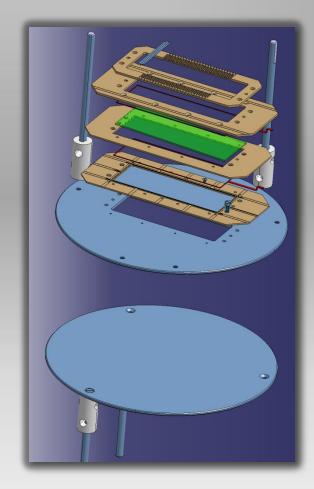








BIPM : Mechanicals



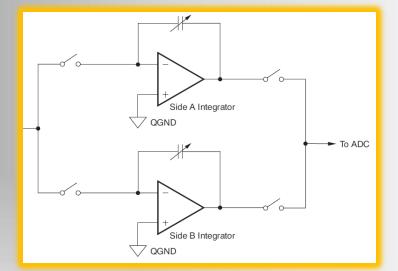
- Roland Sautier Original design
- Readout of 50 stainless tubes with a pitch of 1 mm.
- Brown : WESPEL; insulator and readout support.
- Blue : Stainless Electrode .
- White: MACOR ceramic support.
- Red : MCP Copper Electrode.
- Green : Photonis® simple stack MCP





BIPM : Electronics

- New electronic has been built around DDC264 component which included multi-channels double integrator and ADCs.
- The system is based on a VME BUS crate which drives 2 ISEG® HV VME board (+&- 6kV/4 ch) and 2 VIPMs home made VME board (V&H).

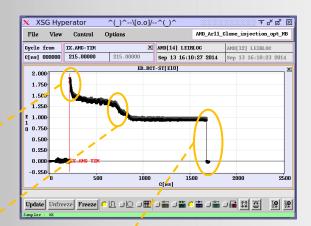


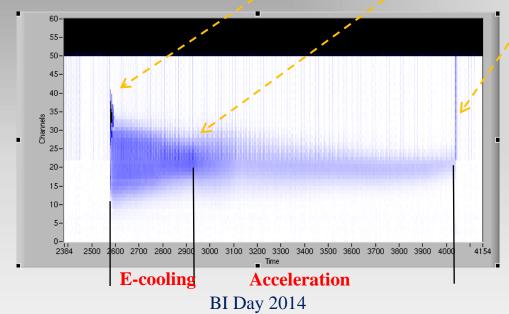




BIPM : Results

- First result V:
 - with a sampling @ 1kHz,
 - Without HV fine tune,
 - Without data processing.











- HV Switch :
 - More studies and tests need to be done in order to understand the virtual perveance.
 - Due to the operating range of AD machine (300mev/c => 100mev/c), High Voltage switch could be used anyway with a different timing.
- IPM
 - First results show that electronics / installations are validated.
 - Some Software layers have to be finished before delivering a secured equipment for the operation.
 - Test still required on the AD machine (gas injection, checking of performance, MCP double stack ...)





Conclusion



